

LASER-ASSISTED SOLAR-CELL METALLIZATION PROCESSING

WESTINGHOUSE ELECTRIC CORP.

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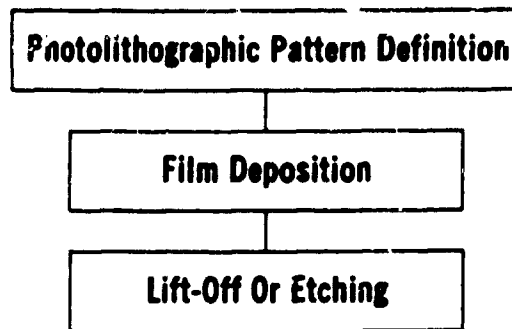
Milestone Chart

Tasks/Milestones	1983				1984								
	S	O	N	D	J	F	M	A	M	J	J	A	S
1. Conduct Literature Search On Current State-Of-The Art Laser Metallization Schemes	→▲												
2. Assemble And Test Each Of The Following Systems:													
2.1 Photolytic metal deposition using a focused CW UV laser							▲		▲				
2.2 Photolytic metal deposition using a mask and UV flood illumination					▲				▲				
2.3 Pyrolytic metal deposition using a focused CW laser								▲					
3. Fabricate Fifty Solar Cells										▲		▲	
4. Characterize The Cells And Determine The Effects Of Transient Heat On Solar Cell Junctions And On Bulk Lifetime												▲	
5. Compare Economics Of Laser Assisted Processing With Competing Technologies													
Preliminary Report					▲								
Final Report													▲
6. Support Meetings													
7. Provide Documentation													

As Directed By JPL

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## PROCESS DEVELOPMENT



**Laser-Assisted Metallization Techniques Are Essentially One-Step Processes:**



### **Potential Advantages of Laser Deposition Techniques for Photovoltaic Systems**

- **High Resolution**
- **No Photolithography**
- **Clean And Contamination - Free**
- **In-Situ Sintering**
- **Low Contact Resistance**

**Laser-Assisted Deposition Techniques**

**Pyrolytic Deposition (Thermal)**

- **Laser Chemical Vapor Deposition (LCVD)**
- **Laser Deposition From Solutions**

**Photolytic Deposition (Non-Thermal)**

- **Laser Photodissociation Of Vapors**
- **Laser Photodissociation Of Solutions**

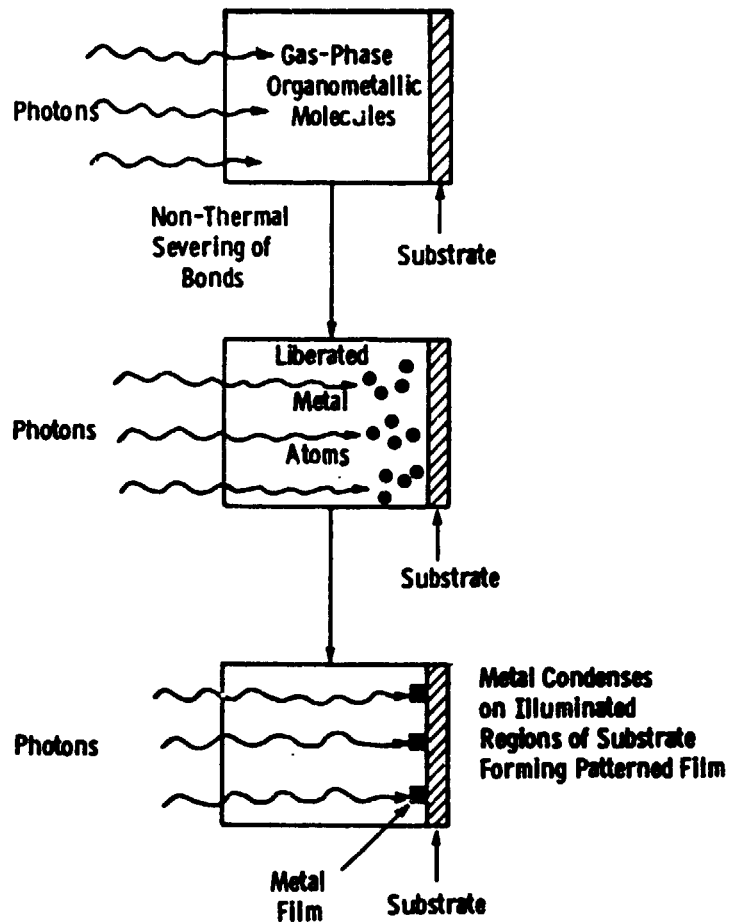
**Laser Assisted Electroplating**

# PROCESS DEVELOPMENT

## Photolytic Deposition

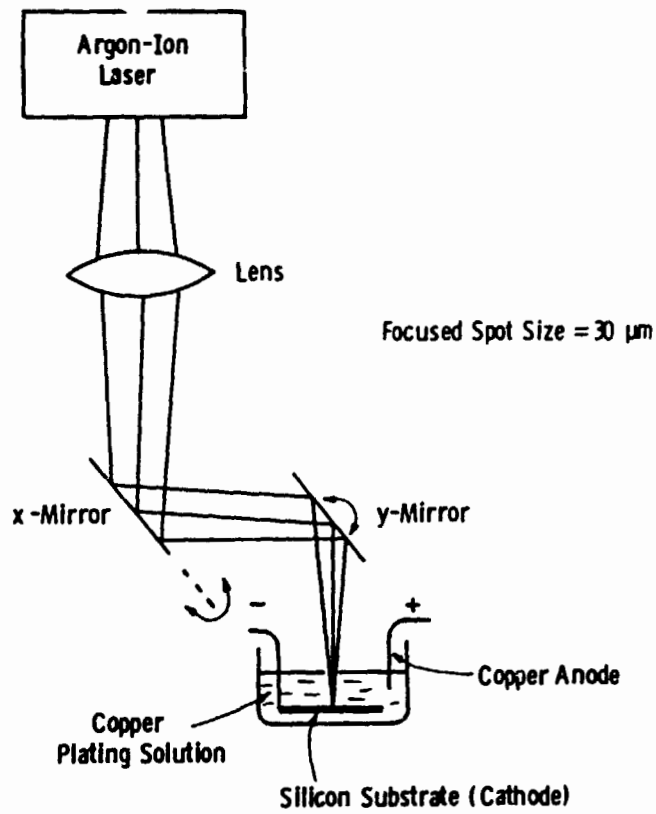
Laser-Induced Photodecomposition of Gas-Phase Organometallic Compounds:

This Technique is Fundamentally Different from Thermally Based Laser Processes



PROCESS DEVELOPMENT

Experimental Setup for Laser-Assisted Electroplating

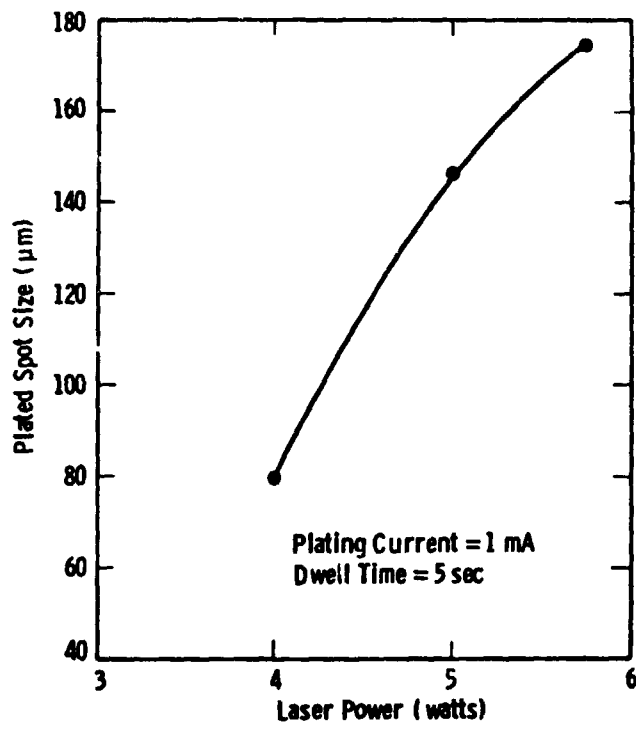


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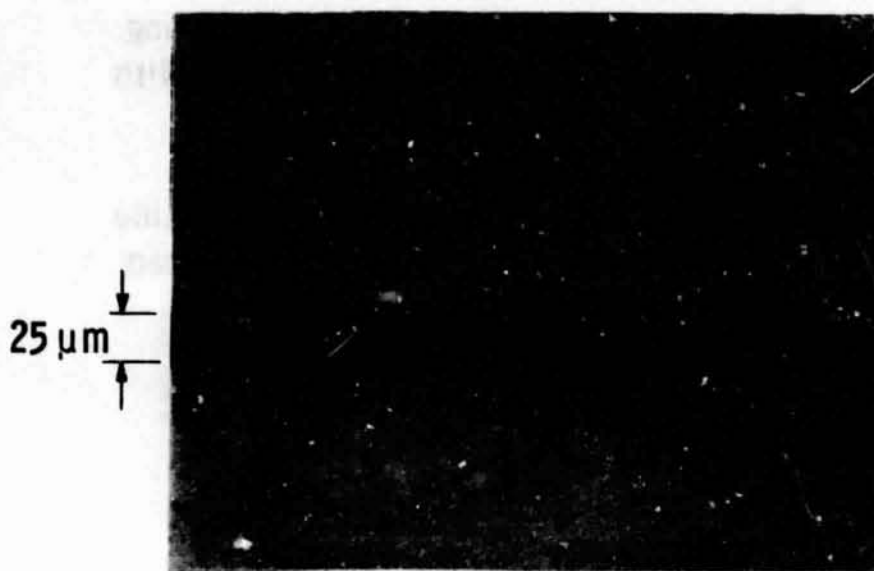
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# PROCESS DEVELOPMENT

## Laser Power Dependence of Electroplated Spot Size



Nomarski Micrograph (200X) of Copper Line  
Deposited by Laser-Assisted Electroplating Results



Linewidth = 25 μm

Line Thickness = 6000 Å

Laser Power = 4 W

Plating Current = 2 mA

Laser Dwell Time = 50 μsec

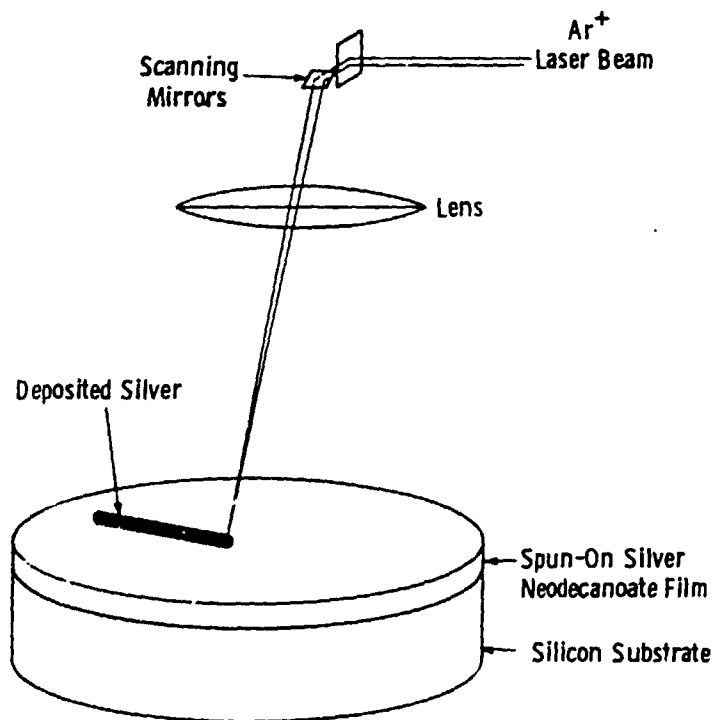
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## PROCESS DEVELOPMENT

### Summary of Laser-Assisted Electroplating Results

- **Novel Technique For Greatly Enhancing Local Plating Rates – Yield Fine-Line, Directly-Written Patterns With Excellent Adhesion**
- **Multiple Rapid Laser Scans Yield Finer, More Even Line And Higher Local Plating Rate Than Single Slow Scan (Same Total Exposure Time)**
- **Plated Linewidth Depends On Laser Power, Plating Current, And Electrolyte Level**

### Laser Pyrolysis of Spun-on Metallo-Organic Film



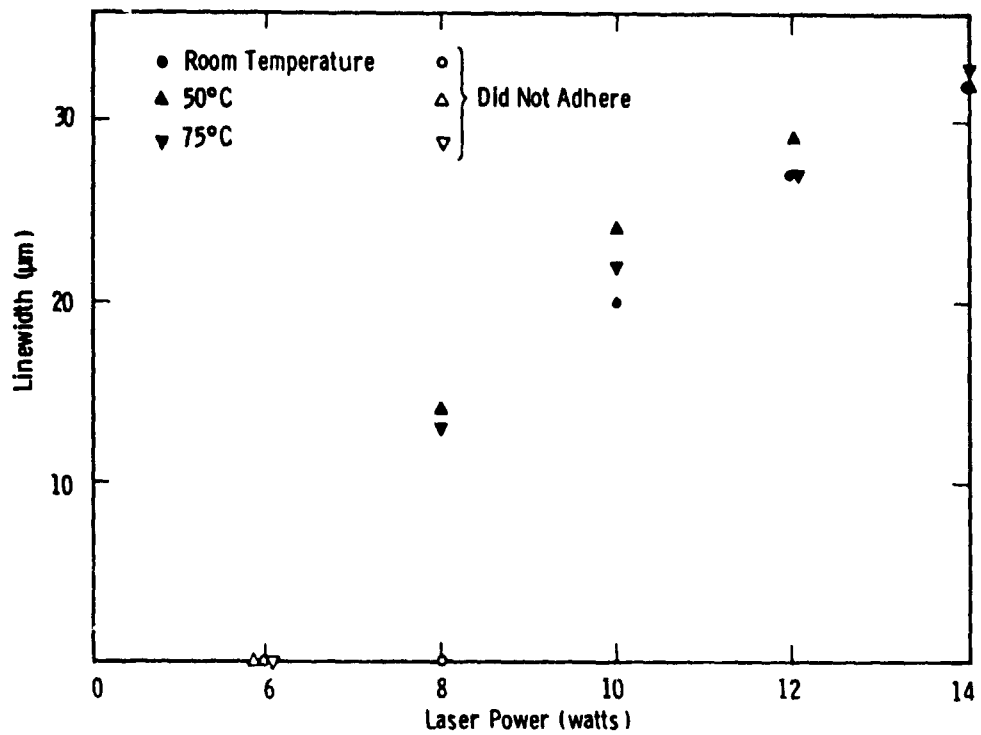
Sample Base Temperature 75°C

Focussed Laser Spot Decomposes Spun-On Film

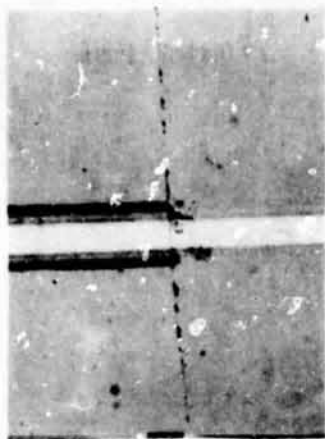
Silver Metallization: Patterns are Formed by Direct-Writing



Line Width vs Laser Power and Substrate Temperature



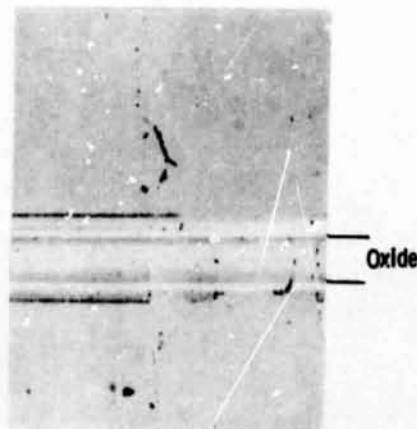
Nomarski Micrographs (200X) of Silver Lines Decomposed  
at (a) 4 W, (b) 8 W, (c) 14 W Before & After Tape Test



(a) ← Scotch Tape Tested



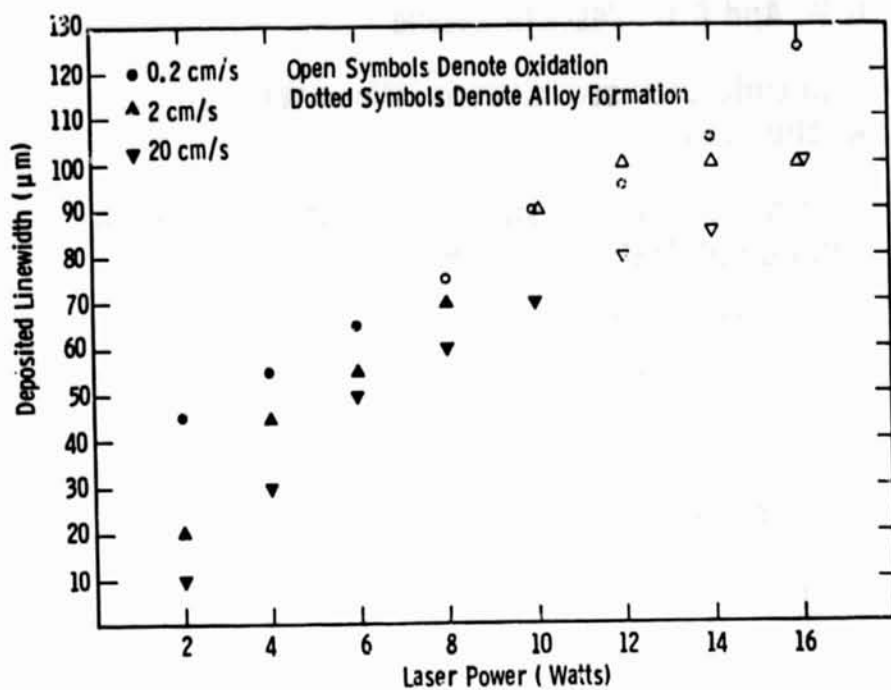
(b) ← Scotch Tape Tested



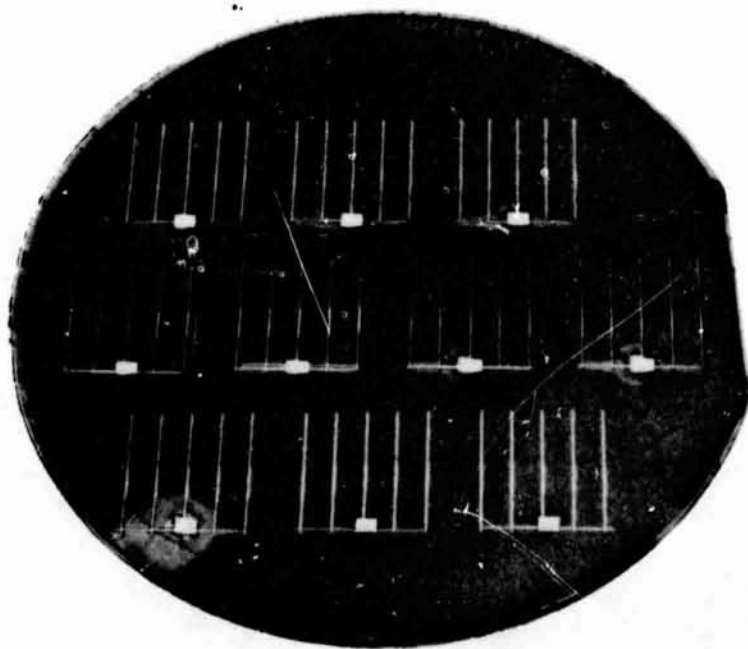
(c) ← Scotch Tape Tested

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### Deposited Line Widths as a Function of Scan Speed and Laser Power



### Laser-Written Solar-Cell Metallization Patterns Using Spun-on Silver Neodecanoate



## PROCESS DEVELOPMENT

### Laser Metallization Process

1. **Make Solution Of Silver Neodecanoate (Obtained From G.M. And R.W. Vest) In Xylene**
2. **Spin Onto Diffused, Coated Silicon Wafers At 1000 rpm**
3. **Decompose Film Locally With Argon-ion Laser To Form Comb Metallization Patterns**
  - Laser Power = 8W
  - Spot Size = 50  $\mu\text{m}$
  - Scan Speed = 20 cm/s
  - Scan Overlap (Contact Pads) = 60%
  - Deposited Silver Thickness = 400 Å
4. **Electroplate Selectvely Onto Patterns**
  - Plated Silver Thickness = 8  $\mu\text{m}$
5. **Define Mesas To Isolate Cells And Characterize Cells**

## Lighted I-V Data for Unsintered Laser-Metallized Cells

Cell I.D.	Short-Circuit Current $J_{sc}$ (mA)	Open-Circuit Voltage $V_{oc}$ (V)	Fill Factor	Efficiency (%)
Laser 1-2	23.1	0.557	0.761	9.8
Laser 1-3	22.8	0.558	0.755	9.6
Laser 1-6	23.7	0.557	0.776	10.3
Laser 1-7	23.7	0.556	0.770	10.1
Laser 1-8	23.7	0.559	0.764	10.1
Laser 1-9	24.2	0.560	0.764	10.3
Laser 1-10	24.2	0.558	0.772	10.4
Laser 1-11	23.8	0.553	0.774	10.2
Laser 1-12	24.2	0.558	0.773	10.4
Laser 1-14	24.6	0.558	0.769	10.5
Laser 1-15	24.5	0.562	0.755	10.4
Laser 5-7	24.3	0.562	0.734	10.0
Laser 5-10	24.7	0.562	0.650	9.0
Laser 5-11	24.7	0.566	0.751	10.5
Laser 5-14	24.6	0.567	0.762	10.6
Laser 5-15	25.1	0.570	0.776	11.1

**PROCESS DEVELOPMENT**

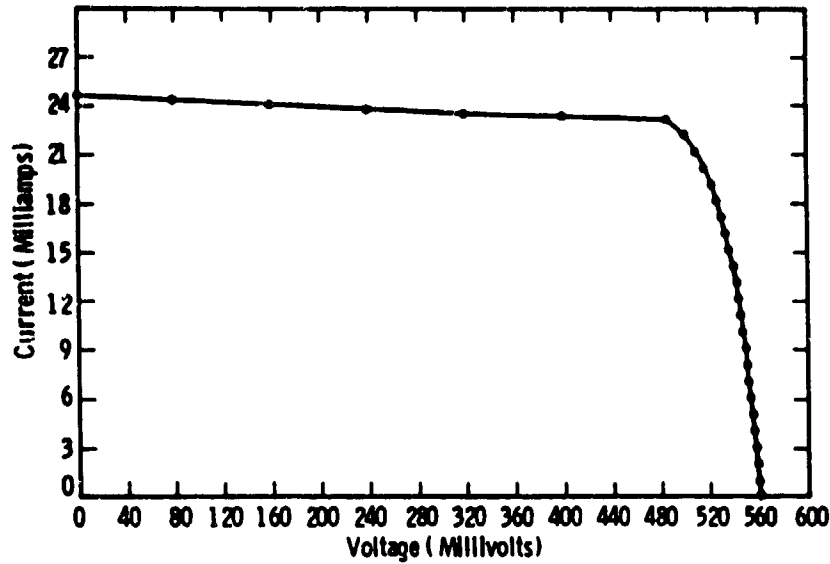
**Lighted I-V Data for Unsintered Baseline Cells**

<b>Cell I.D.</b>	<b>Short-Circuit Current <math>J_{sc}</math> (mA)</b>	<b>Open-Circuit Voltage <math>V_{oc}</math> (V)</b>	<b>Fill Factor</b>	<b>Efficiency (%)</b>
RSC 1-2	23.4	0.573	0.772	10.4
RSC 1-3	23.2	0.562	0.681	8.9
RSC 1-5	23.4	0.571	0.762	11.0
RSC 1-6	25.0	0.569	0.746	10.6
RSC 1-7	25.0	0.567	0.718	10.2
RSC 1-8	24.6	0.571	0.734	10.3
RSC 1-9	23.5	0.568	0.751	10.0
RSC 1-10	25.4	0.569	0.768	11.1
RSC 1-11	25.6	0.568	0.734	10.7
RSC 1-12	25.9	0.567	0.710	10.5
RSC 1-14	26.1	0.571	0.716	10.6
RSC 1-15	25.9	0.567	0.608	8.9
RSC 2-2	25.8	0.569	0.764	11.2
RSC 2-3	26.1	0.567	0.746	11.1
RSC 2-5	26.3	0.569	0.719	10.8
RSC 2-6	25.9	0.566	0.759	11.1
RSC 2-7	25.8	0.566	0.753	11.0
RSC 2-8	25.6	0.567	0.735	10.7
RSC 2-9	25.6	0.566	0.722	10.5
RSC 2-10	25.9	0.566	0.749	11.0
RSC 2-14	26.1	0.567	0.702	10.4
RSC 2-15	26.0	0.567	0.636	9.4

**Comparison of Laser-Metallized and Baseline  
Cells Lighted I-V Data**

<b>Cell I.D.</b>	<b>Short-Circuit Current <math>J_{sc}</math> (mA/cm<sup>2</sup>)</b>	<b>Open-Circuit Voltage <math>V_{oc}</math> (V)</b>	<b>Fill Factor</b>	<b>Non-AR-Coated Cell Efficiency (%)</b>
Laser 1-14	24.6	0.558	0.769	10.5
Baseline 2-9	25.6	0.566	0.722	10.5
Laser 5-11	24.7	0.566	0.751	10.5
Baseline 1-12	25.9	0.567	0.710	10.5
Laser 5-14	24.6	0.567	0.762	10.6
Baseline 1-6	25.0	0.569	0.746	10.6
Laser 5-15	25.1	0.570	0.776	11.1
Baseline 2-3	26.1	0.567	0.746	11.1

Lighted I-V Characteristics of Laser-Metallized Solar Cell



Dark I-V Data for Baseline Cells

Cell I.D.	Normalized Series Resistance ( $\Omega\text{-cm}^2$ )	Normalized Shunt Resistance ( $K\Omega\text{ cm}^2$ )	$J_{01}$ ( $A/\text{cm}^2$ )	$J_{02}$ ( $A/\text{cm}^2$ )	Efficiency (%)
RSC 1-3 Before Sintering	1.3	0.8	$5.1 \times 10^{-12}$	$2.4 \times 10^{-5}$	8.9
RSC 1-3 After Sintering	0.9	6.9	$4.3 \times 10^{-12}$	$3.8 \times 10^{-6}$	10.1
RSC 1-9 Before Sintering	1.0	4.9	$4.2 \times 10^{-12}$	$8.8 \times 10^{-5}$	10.0
RSC 1-9 After Sintering	0.8	113.7	$4.4 \times 10^{-12}$	$1.3 \times 10^{-6}$	10.9
RSC 1-10 Before Sintering	1.0	$>10^3$	$4.5 \times 10^{-12}$	$1.7 \times 10^{-7}$	11.1
RSC 1-10 After Sintering	0.8	769.9	$4.9 \times 10^{-12}$	$1.1 \times 10^{-6}$	10.9
RSC 1-15 Before Sintering	2.2	2.1	$4.0 \times 10^{-12}$	$4.7 \times 10^{-6}$	8.9
RSC 1-15 After Sintering	0.8	5.8	$4.3 \times 10^{-12}$	$3.5 \times 10^{-6}$	8.9
RSC 2-2 Before Sintering	1.0	$>10^3$	$4.2 \times 10^{-12}$	$8.7 \times 10^{-9}$	11.2
RSC 2-2 After Sintering	0.7	$>10^3$	$4.2 \times 10^{-12}$	$3.1 \times 10^{-8}$	11.3
RSC 2-3 Before Sintering	1.1	0.4	$5.0 \times 10^{-12}$	$3.9 \times 10^{-5}$	11.1
RSC 2-3 After Sintering	0.8	1.3	$4.3 \times 10^{-12}$	$1.1 \times 10^{-5}$	11.1
RSC 2-12 Before Sintering	1.5	$>10^3$	$4.3 \times 10^{-12}$	$1.8 \times 10^{-8}$	7.4
RSC 2-12 After Sintering	1.0	77.6	$3.4 \times 10^{-12}$	$2.4 \times 10^{-5}$	7.0
RSC 2-15 Before Sintering	1.8	$>10^3$	$4.1 \times 10^{-12}$	$9.1 \times 10^{-9}$	9.4
RSC 2-15 After Sintering	1.3	$>10^3$	$3.3 \times 10^{-12}$	$4.9 \times 10^{-8}$	9.3

## PROCESS DEVELOPMENT

### Conclusions

- **High Quality Solar Cells Obtained By Laser Metallization Technique**
  - **Non-AR-Coated Cell Efficiency = 11.1%**
- **In-Situ Sintering Occurs During Laser Writing Process**
  - **Series Resistance Of Laser-Metallized Cells Lower**
- **Finer Lines Should Yield Higher Efficiencies**
  - **Laser-Written Linewidths = 50  $\mu\text{m}$**
  - **Baseline Linewidths = 25  $\mu\text{m}$**
  - **Comparable Efficiencies Despite Greater Cell Shadowing In Laser-Metallized Cells**